

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICE**INFORMATION DISCLOSURE
STATEMENT**Docket Number
10191/2169Application Number
To Be AssignedFiling Date
HerewithExaminer
To Be AssignedArt Unit
To Be AssignedInvention Title
**DEVICE AND METHOD FOR ETCHING A
SUBSTRATE BY USING AN INDUCTIVELY
COUPLED PLASMA**Inventor(s)
Volker BECKER et al.Assistant Commissioner
for Patents
Washington, D.C. 20231

1. In accordance with the duty of disclosure under 37 C.F.R. § 1.56 and in conformance with the procedures of 37 C.F.R. §§ 1.97 and 1.98 and M.P.E.P. § 609, attorneys for Applicants hereby bring the references listed on the attached modified PTO form 1449 to the attention of the Examiner. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.
2. A copy of each patent, publication or other information listed on the modified PTO form 1449 is enclosed, except as otherwise indicated.

Dated:

January 22, 2002

By:

Richard L. Mayer (Reg. No. 42,194)
Richard L. Mayer (Reg. No. 22,490) *for*KENYON & KENYON
One Broadway
New York, N.Y. 10004
(212) 425-7200 (telephone)
(212) 425-5288 (facsimile)

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INFORMATION DISCLOSURE STATEMENT BY APPLICANTS PTO FORM 1449	Atty. Docket No. 10191/2169	Serial No. 10 031842 To Be Assigned
	Applicant(s) Volker BECKER et al.	
	Filing Date Herewith	Group To Be Assigned

U. S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NUMBER	PATENT DATE	NAME	CLASS	SUBCLASS	FILING DATE
	5,648,701*	July 15, 1997	Hooke et al.			
	5,997,687*	December 7, 1999	Koshimizu			

* Listed in Search Report (copy not provided, copy provided by International Searching Authority).

FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION	
						YES	NO
	0 849 766* ✓	June 24, 1998	EP				
	WO 99/50883* ✓	October 7, 1999	PCT				
	WO 97/14177* ✓	April 17, 1997	PCT				
	10-64696* ✓	March 6, 1998	JP				
	42 41 045** ✓	May 26, 1994	DE				
	199 00 179** ✓	February 24, 2000	DE				
	199 19 832** ✓	November 9, 2000	DE				
	197 34 278** ✓	February 25, 1999	DE				
	199 18 392** ✓	November 4, 1999	DE				
	199 27 806** ✓	January 4, 2001	DE				

* Listed in Search Report (copy not provided, copy provided by International Searching Authority).

** Described in Specification

OTHER DOCUMENTS

EXAMINER'S INITIALS	AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.
	Patent Abstracts of Japan, Vol. 1998, No. 08, June 30, 1998

* Listed in Search Report (copy not provided, copy provided by International Searching Authority).

EXAMINER	DATE CONSIDERED
EXAMINER: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	